

FORM PTO-1449 (modified)
 To: U.S. Department of Commerce
 (PM&S FORM PAT-1449)
 Patent and Trademark Office



**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Date: April 16, 2002

Page **1** of **1**

Atty. Dkt. No.	M#	Client Ref.
	284106	P-0293.000-US
Applicant: VAN SCHAIK et al		RECEIVED APR 17 2002 10100 MAIL ROOM
Application No.: 09/988,391		RECEIVED AUG 9 2002 10100 MAIL ROOM
Filing Date: November 19, 2001		
Examiner: Unknown		Group Art Unit: 2878

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
Y5	AR	6,252,648	06/2001	HASE et al.			
	BR						
	CR						
	DR						
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						
	NR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
	OR								
	PR								
	QR								
	RR								
	SR								
	TR								
	UR								
	VR								
	WR								
	XR								

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

YR				
ZR				
AAR				
BBR				
CCR				
DDR				

Examiner *Paul Mengo* Date Considered: *5/19/03*

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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**INFORMATION DISCLOSURE STATEMENT
 BY APPLICANT**

Date: December 31, 2002

Page **1** of **1**

Applicant: VAN SCHAIK et al

Application No.: 09/988,391

Filing Date: November 19, 2001

Examiner: Unknown Group Art Unit: 2878

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
PG	AR 6,387,602	05/2002	HAYDEN et al.			
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FOREIGN PATENT DOCUMENTS

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					Enclosed	No	Enclose	No
KR								
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DDR				

Examiner

Paul Gunzo

Date Considered:

5/19/03

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284106 P-0293.000-US

Applicant: VAN SCHAIK et al

Application No.: 09/988,391

Filing Date: November 19, 2001

Examiner: Unknown Group Art Unit: 2878

Date: September 13, 2002

Page 1 of 1

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Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
PG	AR	6,411,368	06/2002	MATSUMOTO et al.			
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	HR						
	IR						
	JR						

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		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
PG	KR	0 660 188 A1	06/1995	EUROPE	STRAAIJER et al.				
	LR								
	MR								
	NR								
	OR								
	PR								
	QR								

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

PG	RR	Bloomstein et al., "UV Cleaning of Contaminated 157-nm Reticles," <i>Proceedings of SPIE</i> 4346:669-375 (2001)		
PG	SR	Liberman, "Reticle Materials Testing Facilities at MIT Lincoln Laboratory," presented March 9, 2000		
PG	TR	Bloomstein et al., "UV Cleaning of Contaminated Reticles," presented August 1, 2000		
PG	UR	Bloomstein et al., "Studies of Laser Induced Contamination and Cleaning," presented November 21, 2000		
PG	VR	Bloomstein et al., "Optical Materials and Coatings at 157 nm," <i>Proceedings of SPIE</i> 3676:342-349 (1999)		
PG	WR	Bloomstein et al., "Laser Cleaning of Optical Elements in 157-nm Lithography," <i>Proceedings of SPIE</i> 4000:1537-1545 (2000)		
PG	XR	Bloomstein et al., "Controlled Contamination of Optics Under 157-nm Laser Irradiation," <i>Proceedings of SPIE</i> 4346:685-694 (2001)		

Examiner *Paul Bumgard* Date Considered: *5/19/03*

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